

Notice of References CitedApplication No.
09/037,945Applicant(s)
Fazan et alExaminer
George FoursonGroup Art Unit
2814

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U.S. PATENT DOCUMENTS

		DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS
	A					
	B					
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	F					
	G					
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		DOCUMENT NO.	DATE	COUNTRY	NAME	CLASS	SUBCLASS
	N	266,885	4/89	Germany	Cattus	----	----
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	U	Miyoshi, H., et al., "Selective Oxidation of Silicon in High Pressure Steam", Journal of the Electrochemical Society, Vol.125, No.11, pp.1824-1828	11/78
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